



00684.002979.1

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:) Examiner: R. E. Fuller
Eiichi MURAKAMI et al.) Group Art Unit: 2851
Application No.: 10/642,699) Confirmation No.: 2740
Filed: August 19, 2003) Allowed: November 18, 2004
For: PROJECTION EXPOSURE APPARATUS) February 18, 2005

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Sir:

Further to the Information Disclosure Statement filed on August 19, 2003, in compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the document listed on the enclosed PTO-1449 form.

U.S. Patent No. 5,142,132 to MacDonald et al. shows an exposure apparatus having an interferometer. Specifically, in the exposure apparatus in this patent, a reticle 20 is illuminated with light from a light source 2 and a pattern of the reticle is projected onto a wafer by a projection optical system 8, 10. An interferometer 12 is provided, with which aberration of the projection optical system can be measured. The measured aberration can be corrected by use of a mirror 6. In the interferometer 12, reference light from a beam splitter 4 and reflection from the wafer interfere with each other. This is shown in Figure 1

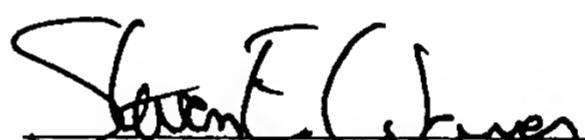
of the MacDonald et al. patent, and is discussed at column 4, lines 10-19, and at column 5, lines 31-58.

Applicants request that the cited information be considered by the Examiner and that a copy of the enclosed PTO-1449 Form be initialed and returned indicating that such information has been considered.

No fee is believed to be due with the filing of this paper. Nevertheless, the Commissioner is authorized to charge Deposit Account No. 06-1205 should any fee be deemed necessary for filing this paper.

Applicants' undersigned attorney may be reached in our Washington D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicants
Steven E. Warner
Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200

SEW/eab



FORM PTO 1449 (modified)		ATTY DOCKET NO. 00684.002979.1		APPLICATION NO. 10/642,699		
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE						
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)		APPLICANT Eiichi MURAKAMI				
Filed: February 18, 2005		FILING DATE August 19, 2003			GROUP 2851	
U.S. PATENT DOCUMENTS						
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS
		US-5,142,132	08/25/1992	MacDonald et al.	250	201.9
FOREIGN PATENT DOCUMENTS						
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)						
EXAMINER			DATE CONSIDERED			

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.